

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)
Koichiro TANAKA, et al.) Group Art Unit: 3742
Application No. 10/769,820) Examiner: Samuel M. Heinrich
Filed: February 3, 2004) Confirmation No. 9528
For: LASER IRRADIATION STAGE, LASER)
IRRADIATION OPTICAL SYSTEM, LASER
IRRADIATION APPARATUS, LASER
IRRADIATION METHOD, AND METHOD OF
MANUFACTURING A SEMICONDUCTOR
DEVICE)

SUBMISSION OF FORMAL DRAWINGS

MAILSTOP: Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Submitted herewith are four (4) sheets of formal drawings, consisting of Figures 4A, 4B, 6, 7A, 7B, 8A and 8B, for filing in the subject application.

Respectfully submitted,

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